

WEST Search History

DATE: Wednesday, November 13, 2002

Set Name Query

side by side

Hit Count Set Name

result set

DB=USPT,JPAB,EPAB,DWPI; PLUR=YES; OP=ADJ

L9	((semiconductor or wafer) same (clean\$3 or etch\$3)) and (gas same bubbl\$3 same scrub\$5)	38	L9
L8	(semiconductor or wafer) same (clean\$3 or etch\$3) same (gas with bubbl\$3) same scrub\$5	4	L8
L7	(gas same bubbl\$3 same scrub\$5)	1079	L7
L6	(gas same bubl\$3 same scrub\$5)	0	L6
L5	(clean\$3 or etch\$3) and (gas same bubl\$3 same scrub\$5)	0	L5
L4	((semiconductor or wafer) same (clean\$3 or etch\$3)) and (gas same bubl\$3 same scrub\$5)	0	L4
L3	(semiconductor or wafer) same (clean\$3 or etch\$3) same (gas with bubl\$3) same scrub\$5	0	L3
L2	((semiconductor or wafer) with (clean\$3 or etch\$3)) same((gas adj3 bubl\$3) with scrub\$5)	0	L2
L1	(semiconductor or wafer) with (clean\$3 or etch\$3) with(gas adj3 bubl\$3) with scrub\$5	0	L1

END OF SEARCH HISTORY